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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: **Miwa KOZAWA et al.**

Group Art Unit: **1752**

Application Number: **10/629,806**

Examiner: **Sin J. Lee**

Filed: **July 30, 2003**

Confirmation Number: **9494**

For: **RESIST PATTERN THICKENING MATERIAL, PROCESS FOR
FORMING RESIST PATTERN, AND PROCESS FOR
MANUFACTURING SEMICONDUCTOR DEVICE**

Attorney Docket Number: **030923**

Customer Number: **38834**

INFORMATION DISCLOSURE STATEMENT
UNDER 37 C.F.R. §1.97(c)(1)/(e)(1)

Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

May 4, 2006

Sir:

Applicants direct the attention of the Patent and Trademark Office to the documents listed on the attached Form PTO/SB/08. A copy of each non - U.S. document is attached.


This Information Disclosure Statement (IDS) is being submitted after issuance of a first official action on the merits and expiration of the three month period following the filing date or the entry of the national stage for the above-captioned application, but prior to issuance of either a final official action or a Notice of Allowance.

The undersigned hereby certifies that each item of information contained in the IDS was first cited in any communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of the IDS. A copy of the foreign communication citing the documents is attached.

Information Disclosure Statement under 1.97(c)(1)
Attorney Docket No. 030923
Application No. 10/629,806

If there are any fees due in connection with the filing of this paper, please charge Deposit
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Respectfully submitted,
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